

PROCESSING

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RAPID THERMAL PROCESSING OF CZOCHRALSKI SILICON SUBSTRATES: DEFECTS, DENUDED ZONES, AND MINORITY CARRIER LIFETIME

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Rapid Thermal Processing of Czochralski Silicon: Objectives

To evaluate rapid thermal processing as a viable procedure for:

1. Czochralski substrate modification using high temperature defect-dissolution treatments,
2. Rapid junction activation following ion implantation

Diagnostic Tools

1. MOS Capacitor -- minority carrier lifetime
2. X-Ray Topography -- defect delineation
3. Nomarski Optical Microscopy & Preferential Chemical Etching -- defect delineation
4. Fourier Transform Infrared Microscopy -- oxygen precipitation kinetics

Metal Oxide Semiconductor Capacitor - C

1. Capacitance-voltage (C-V) measurements
2. Capacitance-time (C-t) measurements
3. C-V, C-t measurements at different temperatures T
4. Minority carrier generation and recombination lifetime (τ_g and τ_r)

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Change of Inversion Layer Charge Density with Time

$$\frac{dn_s}{dt} = \underbrace{\left(\frac{n_i (W - W_F)}{\tau_g} + n_i s \right)}_A + \underbrace{\left(\frac{n_i^2 D_n}{N_A L_n} \right)}_B$$

Room temperature $A \gg B$ (Zerbst, 1966)

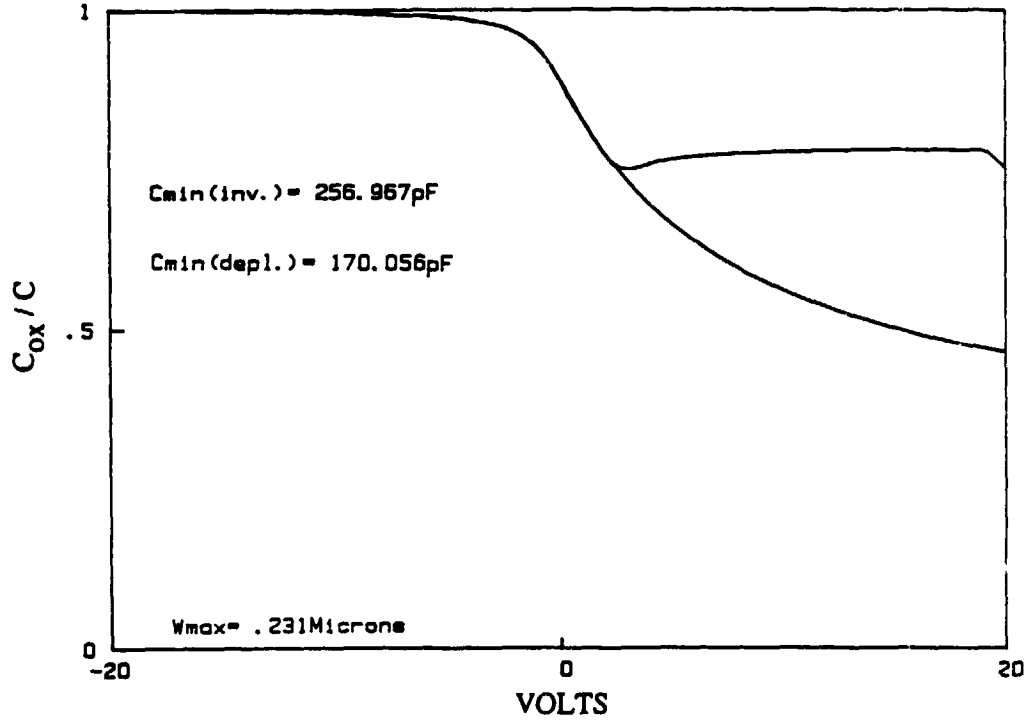
Elevated temperature $A \ll B$ (Schroder, 1984)

- n_s - inversion layer charge density
- W_F - final space charge region width
- W - space charge width
- n_i - intrinsic carrier density
- D_n - diffusion constant
- L_n - diffusion length
- N_A - substrate doping concentration
- τ_g - generation lifetime
- s - surface recombination velocity
- τ_r - recombination lifetime ($\tau_r = L_n^2/D_n$)

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Capacitance Versus Voltage (Sample Y2)

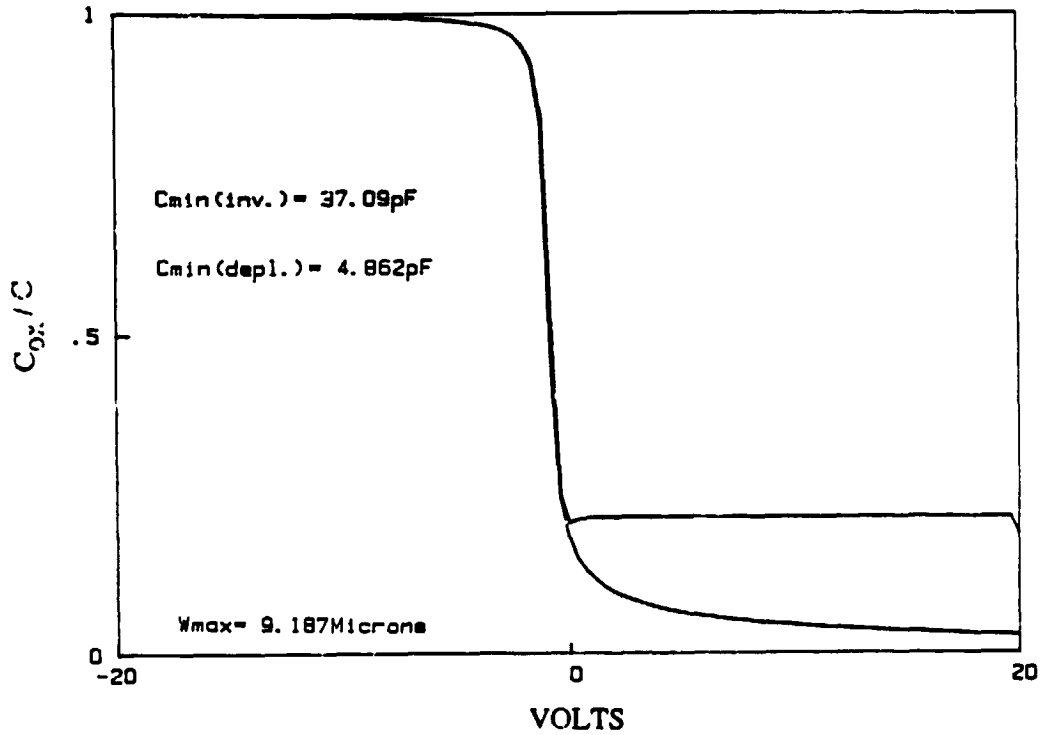
Cox= 340.278pF Cfb= 327.203pF
Cmin/Cmax= .755 Cfb/Cox= .962 Qss= 2.272E+11ions/cm²
Area= 7.58528E-03cm² Vfb(0)=-1.738Volts Sample number = Y2
Nsub= 1.96658E+17cm⁻³ Vt= 4.374Volts



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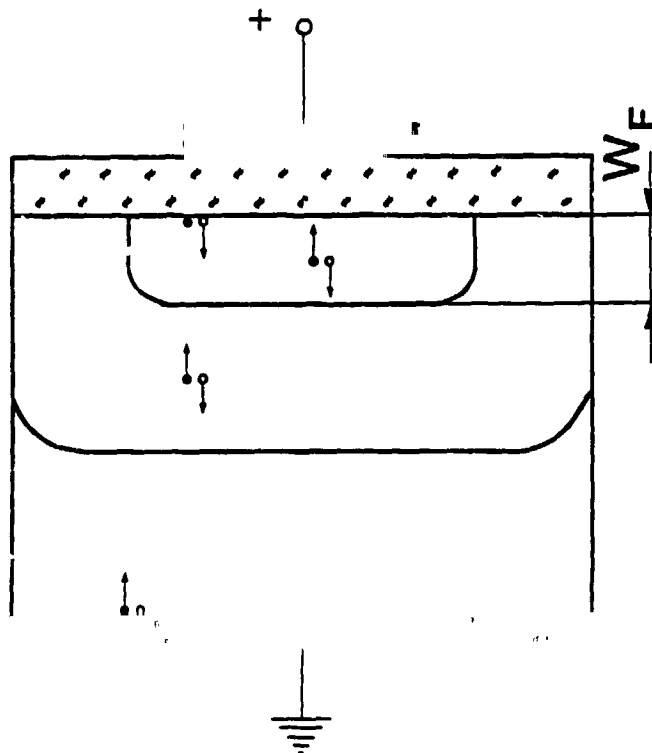
Capacitance Versus Voltage (Sample Z27)

Cox= 188.3pF Cfb= 119.474pF Qss= 3.66E+10ions/cm²
Cmin/Cmax= .187 Cfb/Cox= .602 Sample number = Z27
Area= .0044204cm² Vfb(0)= -.912Volts
Neub= 7.213E+14cm⁻³ Vt= -.091Volts



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Zerbst Analysis (Room Temperature)



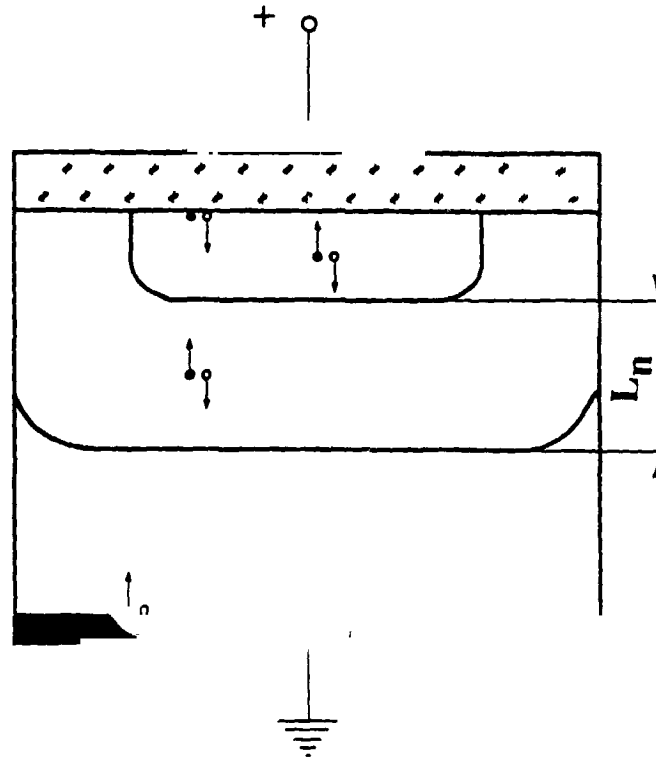
$$\frac{-d(C_{ox}/C)}{dt} \quad \text{vs} \quad \frac{C_F}{C-1}$$

$\tau_g \propto$ slope

$s \propto$ intercept

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Schroder Analysis (Elevated Temperature)



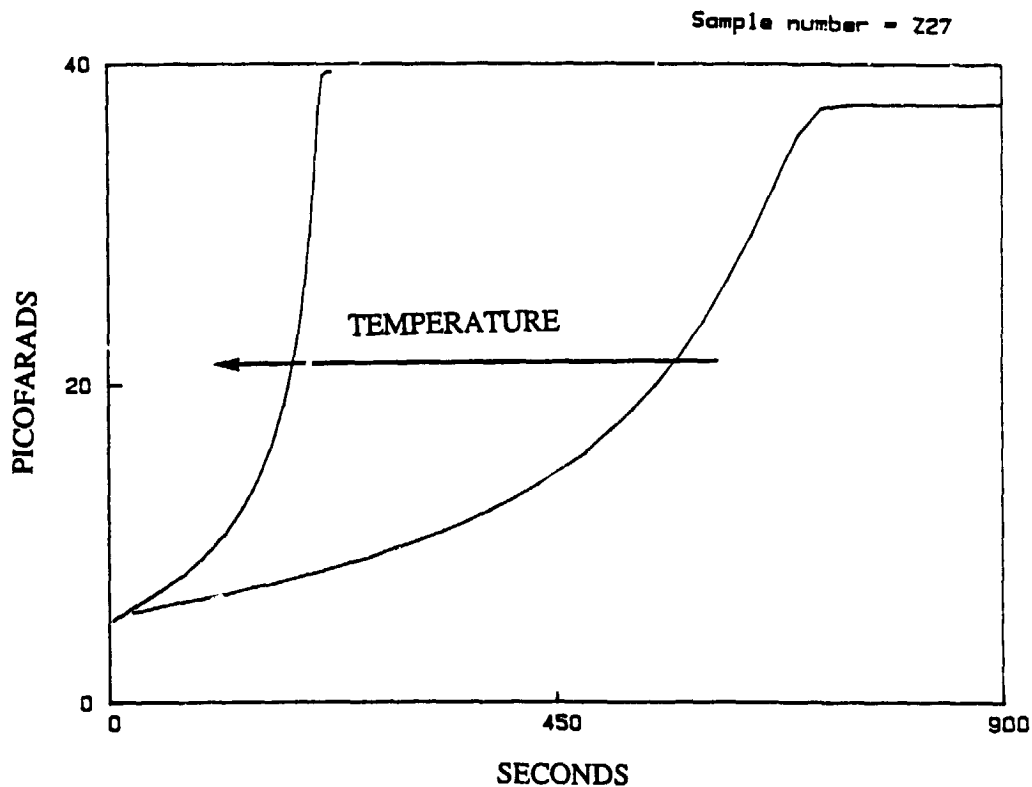
$1 - (C_F/C)^2$ vs time

$$\tau_r \propto L_n^2$$

$$L_n \propto \text{slope}$$

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Capacitance Versus Time (Sample Z27)



X-Ray Topography

1. X - Ray Source: Marconi-Elliot GX-21
(15kW, Rotating anode)
2. Cameras: - Lang Transmission
- Double Crystal
3. Sample treatment conditions:
 - i. Virgin
 - ii. Lo-Hi + RTP combination
 - iii. Li decoration

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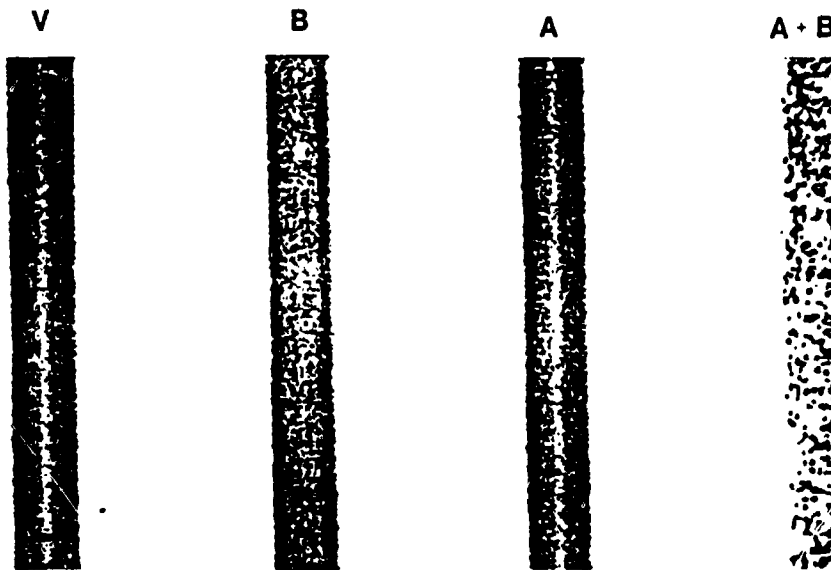
Surface Recombination Velocity/X-Ray Topography

MoK α 220 X30

V: Virgin

A: 700°C / 16h dry O₂ + 0.0425HCL

B: 1100°C / 10min dry O₂ + 60minwet O₂ + 10mindry O₂



Nomarski Optical Microscopy and Preferential Chemical Etching

Etchant: Secco

- Observation:
1. Depth of denuded zone (DZ)
 2. Density and size of oxygen precipitates, stacking faults and dislocation.

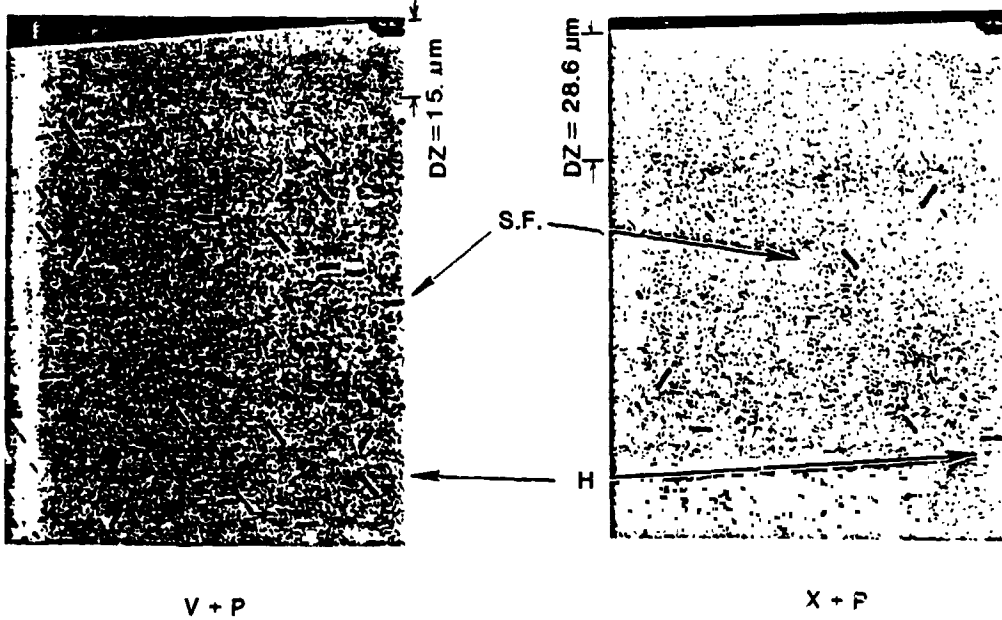
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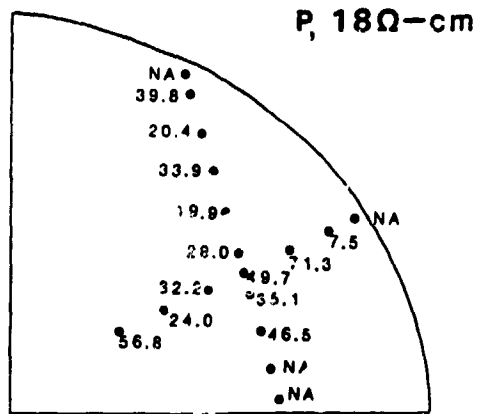
P: 700°C/16h dry O₂+2% HCl+1100°C/(10min: dry+65min wet+10min)O₂+2% HCl
+1100°C/15min dry O₂+2% HCl

V: Virgin

X: RTA 1200°C/2 min Ar



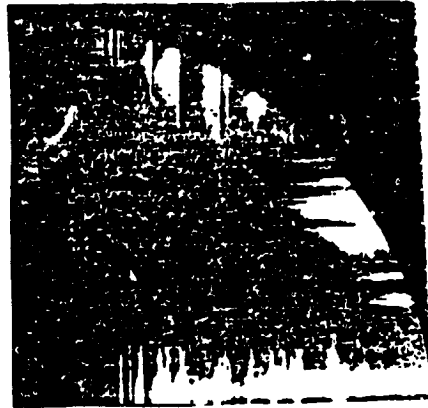
Minority Carrier Lifetime (Units in μs)



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Heat Treatment

RTP(1200°C/2min) in Ar
+1100°C/(10min dry+65min wet+10min dry)O₂



Heat Treatment of Samples

- A : 700°C/16h dry O₂ + 2% HCl
- B : 1100°C/(10 min dry+65 min wet+10 min dry)O₂ + 2% HCl
- C : 1100°C/15 min dry O₂

- V : Virgin
- X : RTP 1200°C/2 min in Ar
- Y : 1200°C/30 min in Ar
- Z : 1250°C/30 min in dry O₂ + 2% HCl
- w : 1250°C/30 min in Ar

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Arrays of Heat Treatments

| | C | A+C | B+C | A+B+C |
|---|-----|-------|-------|---------|
| V | V+C | V+A+C | V+B+C | V+A+B+C |
| X | X+C | X+A+C | X+B+C | X+A+B+C |
| Y | Y+C | Y+A+C | Y+B+C | Y+A+B+C |
| Z | Z+C | Z+A+C | Z+B+C | Z+A+B+C |
| W | W+C | W+A+C | W+B+C | W+A+B+C |

Heat Treatment of Samples

- A : 700°C/16h dry O₂ + 2% HCl
- B : 1100°C/(10 min dry+65 min wet+10 min dry)O₂ + 2% HCl
- C : 1100°C/15 min dry O₂ + 2% HCl

- | | | |
|---|---|-----------|
| V : Virgin | } | C |
| X : RTP 1200°C/2 min in Ar | | A + C |
| Y : 1200°C/30 min in Ar | | B + C |
| Z : 1250°C/30 min in dry O ₂ + 2% HCl | | A + B + C |
| W : 1250°C/30 min in Ar | | |

Minority Carrier Lifetime (τ_g , μ s)

| | | | |
|----------|-------|------|---------|
| | V+C | X+C | X+A+B+C |
| Group Z1 | 111.0 | 15.6 | 83.8 |
| Group Z2 | 57.5 | 85.7 | 159.0 |
| | V+C | Z+C | Z+A+B+C |